

**PATENT APPLICATION**  
**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re application of

Docket No: Q87267

Masahiko HATA

Appln. No.: 10/530,562

Group Art Unit: 1792

Confirmation No.: 8996

Examiner: Robert M. Kunemund

Filed: April 7, 2005

For: METHOD FOR PRODUCING THIN FILM CRYSTAL WAFER, SEMICONDUCTOR  
DEVICE USING THE SAME AND METHOD FOR PRODUCING THE  
SEMICONDUCTOR DEVICE

**PETITION FOR EXTENSION OF TIME UNDER 37 C.F.R. § 1.136**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Pursuant to 37 C.F.R. § 1.136, Applicant hereby petitions for an extension of time of three months, extending the time for responding to the Office Action of January 8, 2010 to July 8, 2010.

The USPTO is directed and authorized to charge the statutory fee of \$1110.00 and all required fees, except for the Issue Fee and the Publication Fee, to Deposit Account No. 19-4880. Please also credit any overpayments to said Deposit Account.

Respectfully submitted,

/Hui C. Wauters/

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WASHINGTON OFFICE

**23373**

CUSTOMER NUMBER

Date: July 8, 2010